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Appl. No. 10/650,601 Amdt. dated 12/02/2005 Reply to Office Action of 10/04/2005

RECEIVED CENTRAL FAX CENTEROMEY Docket No.: TS01-999 N1085-90151

JAN 1 6 2006

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Shi-Chi Lin

Examiner: José R. Diaz

Serial No.: 10/650.601

Group Art Unit: 2815

Filed: August 28, 2003

Confirmation No.: 8321

For METHOD OF MANUFACTURING DIELECTRIC ISOLATED SILICON

STRUCTURE

I hereby certify that this document (and any documents referred to therein) are being sent by facsimile to (571) 273-8300 addressed to the following:

> Examiner Jose R. Diaz Commissioner for Patents P. O. Box 1450 Alexandria, VA 22313-1450

Date: December 2, 2005

To I wer and

Maria E. Provencio

Examiner José R. Diaz Mail Stop Non-Fee Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

RESPONSE TO OFFICE ACTION DATED OCTOBER 4, 2005

Sir:

Responsive to the final Office Action dated October 4, 2005, please re-examine and reconsider the above-identified application according to the amendments and remarks provided.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.

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